

U.S. DEPARTMENT OF COMMERCE

PATENT AND TRADEMARK OFFICE

LIST OF REFERENCES CITED BY APPLICANT(S)

(Use several sheets if necessary)

Date Submitted to PTO: October 23, 2001

ATTY DOCKET NO.

862.C2171

APPLICATION NO.

09/819,672

APPLICANT

Takayuki YAGI, et al.

FILING DATE

March 29, 2001

GROUP

2878

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
EN	5,834,783	11/10/1998	Muraki, et al.	250	398	
	5,864,142	01/26/1999	Muraki, et al.	250	491.1	
	5,905,267	05/18/1999	Muraki	250	492.22	
	5,981,954	11/09/1999	Muraki	250	397	
	6,107,636	08/22/2000	Muraki	250	492.2	
	6,104,035	08/15/2000	Muraki	250	492.22	
	6,166,387	12/26/2000	Muraki, et al.	250	492.2	
	5,929,454	07/27/1999	Muraki, et al.	250	491.1	
	5,939,725	08/17/1999	Muraki	250	492.22	
	5,973,332	10/26/1999	Muraki, et al.	250	492.2	
	6,137,113	10/24/2000	Muraki	250	492.22	
EN	4,419,580	12/06/1983	Walker, et al.	250	396 R	

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER

E. MU YEN

DATE CONSIDERED

02-28-03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to applicant.

Sheet 1 of 2

FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE
LIST OF REFERENCES CITED BY APPLICANT(S)(Use several sheets if necessary)
Date Submitted to PTO: October 23, 2001ATTY DOCKET NO.
862.C2171APPLICATION NO.
09/819,672APPLICANT
Takayuki YAGI, et al.FILING DATE
March 29, 2001GROUP
2878

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

len	"Sub-Nanometer Miniature Electron Microscope", A.D. Feinerman, et al., Journal of Vacuum Science and Technology A, Vol. 10, No. 4, July/August 1992, 611-616.
len	"High Aspect Ratio Aligned Multilayer Microstructure Fabrication", K. Y. Lee, et al., Journal of Vacuum Science and Technology B, Vol. 12, No. 6, November/December 1994, pp. 3425-3430.
ten	"Arrayed Miniature Electron Beam Columns For High Throughput Sub-100 nm Lithography", T. H. P. Chang, et al., Journal of Vacuum Science and Technology B, Vol. 10, No. 6, November/December 1992, pp. 2743-2748.
len	"Microstructures for Particle Beam Control", G. W. Jones, et al., Journal of Vacuum Science and Technology B, Vol. 6, No. 6, November/December 1988, pp. 2023-2027.
len	"A Multibeam Scheme for Electron-Beam Lithography", T. Sasaki, Journal of Vacuum Science and Technology, Vol. 19, No. 4, November/December 1981, pp. 963-965.

EXAMINER

len. MUYEN

DATE CONSIDERED

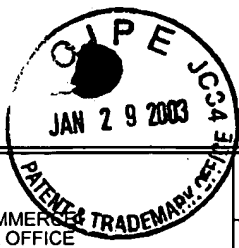
028-28-03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to applicant.

SEW/mj

Sheet 2 of 2



FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)
(Use several sheets if necessary)

January 29, 2003

ATTY DOCKET NO. 00862.022171

APPLICATION NO. 09/819,672

APPLICANT Takayuki YAGI et al.

FILING DATE March 29, 2001

GROUP 2878

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
EN	5,121,234	06/09/1992	Kucera	359	50	
EN	5,604,394	02/18/1997	Saito et al.	313	422	
EN	6,381,702	04/30/2002	Ogasawara	713	500	
	2002/0051111	05/02/2002	Greene et al.	349	149	
↳ this is not considered as the prior art.						

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER	DATE CONSIDERED
EN. MUYEN	02-28-03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

Sheet 1 of 1